Docket No.: SON-2611/DIV

(PATENT)

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Divisional Patent Application of:

Keiichi Kimura et al.

Application No.: Not Yet Assigned

Art Unit: 3723

Filed: March 23, 2004

Examiner: Hadi Shakeri

For: POLISHING METHOD AND POLISHING

APPARATUS

FIRST PRELIMINARY AMENDMENT

MS Patent Application Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

Dear Sir:

INTRODUCTORY COMMENTS

Prior to examination on the merits, please amend the above-identified U.S. patent application as follows:

Amendments to the Specification begin on page 2 of this paper.

Amendments to the Claims are reflected in the listing of claims which begins on page 3 of this paper.

Amendments to the Drawings begin on page 4 of this paper and include both an attached replacement sheet and an annotated sheet showing changes.

Remarks/Arguments begin on page 5 of this paper.